

3600.2406  
October 25, 2002 (1:46PM)

Docket: AM-2406

#19/CMB  
10.30.24

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of: Imran HASHIM et al

Attorneys Docket: AM-2406

Serial No.: 09/138,429

Art Unit No.: 2825

Filed: August 24, 1998

Examiner: J. Mercado

For: "COLLIMATED AND LONG THROW MAGNETRON SPUTTERING OF  
NICKEL/IRON FILMS FOR MAGNETIC RECORDING HEAD APPLICATIONS"

Commissioner of Patents  
Washington, DC 20231

AMENDMENT UNDER 37 CFR §1.116

Sir:

In response to the Office Action of August 27, 2002, please amend the above application as follows:

Replace the claims with:

21. An apparatus for depositing a magnetic film, comprising:

a sputtering chamber containing a target, a substrate support having a substrate surface that is separated from the target, and a grounded collimator positioned between the target and the substrate support; and

an annular magnet array disposed within the sputtering chamber, the annular magnet array being configured to form a magnetic field that is substantially parallel to the substrate surface of the substrate support, the annular magnet array being concentrically positioned around an outer perimeter of the substrate surface of the substrate support.

~~27. A method for depositing a magnetic film within a sputtering chamber containing a~~